

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): OKUDA, et al.

Application No.: 10/018,708

Filed: Dec. 13, 2001

Title: Table of Wafer Polishing
Apparatus, Method for Polishing
Semiconductor Wafer, and Method for
Manufacturing Semiconductor WaferAttorney Docket No.:
P3P2000078US/2369NP


Group Art Unit: 3723

Examiner:

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TECHNOLOGY CENTER 3700Assistant Commissioner for Patents
Washington, D.C. 20231**POWER TO INSPECT/COPY**

Dear Sir:

Please permit B. B. Landsdown of B's Business Service, Inc., to inspect the above-entitled application, and to make copies of any of the papers that she may desire.


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